

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (currently amended) A method for forming a supported palladium membrane used for hydrogen purification and production, comprising steps of:
providing a porous stainless steel support;
mechanically polishing said porous stainless steel support by one of an abrasive paper and an ultrasonic vibration;
electro-polishing said porous stainless steel support;
acid-washing said porous stainless steel support with an acid solution;
activating said porous stainless steel support by heating;
filling said porous stainless steel support with a metal;
electroless plating a palladium membrane on said porous stainless steel support with a palladium salt solution; ~~and~~
DC sputtering an additional palladium membrane further on said porous stainless steel support;
annealing said palladium membrane.
2. (original) The method according to claim 1 wherein said support is a porous stainless steel support.
3. (canceled).
4. (original) The method according to claim 1 wherein said metal is one selected from a group consisting of palladium, niobium, tantalum and a combination thereof.
5. (original) The method according to claim 1 wherein said metal is a hydrogen permeable fine metal powder.
6. (original) The method according to claim 5 wherein said metal powder is mixed with one of a palladium paste and a high temperature epoxy resin.
7. (canceled).

8. (canceled).
9. (original) The method according to claim 1 wherein said palladium salt solution contains 4.2~5.4 g/L $\text{Pd}(\text{NH}_3)_4\text{Cl}_2$, 60~74 g/L EDTA, 600~700 g/L NH_4OH and 0.32~0.4 c.c./L NH_2NH_2 .
10. (original) The method according to claim 1 wherein said electroless plating is performed for 120~360 minutes.
11. (original) The method according to claim 1 wherein said electroless plating is performed at 50~70 °C.
12. (original) The method according to claim 1 wherein a target of said DC sputtering is 99~99.9% palladium.
13. (original) The method according to claim 1 wherein said DC sputtering is performed under a vacuum pressure of 10^{-2} ~ 10^{-5} torr and a power input of 200~500 W at 25~250 °C.
14. (original) The method according to claim 1 wherein said DC sputtering is performed for 60~120 minutes.
15. (original) The method according to claim 1 wherein said palladium membrane has a thickness of 3~30 μm after said DC sputtering.
16. (currently amended) The method according to claim 1 ~~further comprising a step of wherein said annealing said palladium membrane step is performed at a temperature ranged from 450 to ~550 °C under a nitrogen atmosphere including 3~10% a hydrogen concentration ranged from 3% to 10% for a period ranged from 4 to ~8 hours.~~
17. (currently amended) A method for forming a supported palladium membrane used for hydrogen purification and production, comprising steps of:
providing a porous stainless steel support;
mechanically polishing said porous stainless steel support by one of an abrasive paper and an ultrasonic vibration;

electro-polishing said porous stainless steel support;
acid-washing said porous stainless steel support with an acid solution;
activating said porous stainless steel support by heating;
filling said porous stainless steel support with a metal; and
electroless plating a palladium membrane on said porous stainless steel support with a
palladium salt solution; and
annealing said palladium membrane.

18. (currently amended) A method for forming a supported Pd/Ag membrane used for hydrogen purification and production, comprising steps of:
providing a porous stainless steel support;
mechanically polishing said porous stainless steel support by one of an abrasive paper and an ultrasonic vibration;
electro-polishing said porous stainless steel support;
acid-washing said porous stainless steel support with an acid solution;
activating said porous stainless steel support by heating;
filling said porous stainless steel support with a metal;
electroless plating a palladium membrane on said porous stainless steel support with a
palladium salt solution;
electroless plating a silver membrane on said porous stainless steel support with a silver
salt solution;
annealing said palladium membrane and said silver membrane to form a Pd/Ag
membrane; and
DC sputtering an additional Pd/Ag membrane further on said porous stainless steel
support.

19. (original) The method according to claim 18 wherein said support is a porous
stainless steel support.

20. (canceled).

21. (original) The method according to claim 18 wherein said metal is one selected from
a group consisting of palladium, niobium, tantalum and a combination thereof.

22. (original) The method according to claim 18 wherein said metal is a hydrogen permeable fine metal powder.
23. (original) The method according to claim 22 wherein said metal powder is mixed with one of a palladium paste and a high temperature epoxy resin.
24. (canceled).
25. (canceled).
26. (original) The method according to claim 18 wherein said palladium salt solution contains 4.2~5.4 g/L $\text{Pd}(\text{NH}_3)_4\text{Cl}_2$, 60~74 g/L EDTA, 600~700 g/L NH_4OH and 0.32~0.4 c.c./L NH_2NH_2 .
27. (original) The method according to claim 18 wherein said silver salt solution contains 2.1~1 g/L AgNO_3 , 60~74 g/L EDTA, 600~700 g/L NH_4OH and 0.32~0.4 c.c./L NH_2NH_2 .
28. (original) The method according to claim 18 wherein said electroless plating is performed at 50~70 °C.
29. (original) The method according to claim 18 wherein a target of said DC sputtering is a Pd/Ag alloy with a weight composition ratio of 77/23~60/40.
30. (original) The method according to claim 18 wherein said DC sputtering is performed under a vacuum pressure of 10^{-2} ~ 10^{-5} torr and a power input of 200~500 W at 25~250 °C.
31. (original) The method according to claim 18 wherein said step of annealing said palladium membrane and said silver membrane is performed at 450~550 °C under a nitrogen atmosphere including 3~10% hydrogen for 4~8 hours.
32. (original) The method according to claim 18 wherein said palladium membrane has a thickness of 3~30 μm after said DC sputtering.

33. (currently amended) A method for forming a supported Pd/Ag membrane used for hydrogen purification and production, comprising steps of:
providing a porous stainless steel support;
mechanically polishing said porous stainless steel support by one of an abrasive paper and an ultrasonic vibration;
electro-polishing said porous stainless steel support;
acid-washing said porous stainless steel support with an acid solution; and
activating said porous stainless steel support by heating;
filling said porous stainless steel support with a metal;
electroless plating a palladium membrane on said porous stainless steel support with a palladium salt solution;
electroless plating a silver membrane on said porous stainless steel support with a silver salt solution; and
annealing said palladium membrane and said silver membrane to form a Pd/Ag membrane.
34. (new) The method according to claim 1 wherein said acid solution is HCl and said concentration thereof is ranged from 8 to 10 M HCl.
35. (new) The method according to claim 1 wherein said activating step is performed under a temperature ranged from 40 to 60 °C.
36. (new) The method according to claim 17 wherein said acid solution is HCl and said concentration thereof is ranged from 8 to 10 M HCl.
37. (new) The method according to claim 17 wherein said activating step is performed under a temperature ranged from 40 to 60 °C.
38. (new) The method according to claim 17 wherein said annealing step is performed at a temperature ranged from 450 to 550 °C under a nitrogen atmosphere including a hydrogen concentration ranged from 3 to 10% for a period ranged from 4 to 8 hours.
39. (new) The method according to claim 18 wherein said acid solution is HCl and said concentration thereof is ranged from 8 to 10 M HCl.

40. (new) The method according to claim 18 wherein said activating step is performed under a temperature ranged from 40 to 60 °C.
41. (new) The method according to claim 33 wherein said acid solution is HCl and said concentration thereof is ranged from 8 to 10 M HCl.
42. (new) The method according to claim 33 wherein said activating step is performed under a temperature ranged from 40 to 60 °C.
43. (new) The method according to claim 33 wherein said step of annealing said palladium membrane and said silver membrane is performed at a temperature ranged from 450 to 550 °C under a nitrogen atmosphere including a hydrogen concentration ranged from 3 to 10% for a period ranged from 4 to 8 hours.